



Chris A. Mack developed the lithography simulation software PROLITH, and founded and ran the company FINLE Technologies for ten years. After FINLE was acquired by KLA-Tencor in 2000, he served as Vice President of Lithography Technology for KLA-Tencor for five years. In 2003, he received the SEMI Award for North America for his efforts in lithography simulation and education, and in 2009, he received the SPIE Frits Zernike Award for Microlithography. He is a fellow of SPIE and IEEE, and is also an adjunct faculty member at the University of Texas at Austin. In 2012, he became Editor-in-Chief of the *Journal of Micro/Nanolithography, MEMS, and MOEMS* (JM³). In 2017, he cofounded Fractilia, where he now works as Chief Technical Officer, developing metrology solutions for the measurement of roughness.